Experimental and theoretical band-structure studies of refractory metal silicides

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The electronic structures of bulk refractory metal disilicides VSi₂, TaSi₂, and MoSi₂ have been examined using photoelectron spectroscopy with synchrotron radiation. Photoelectron energy distribution curves measured for $9 \le hv \le 140$ eV show occupied bands (full width $\simeq 12$ eV) dominated by metal *d*-derived states within 3–4 eV of E_F and by Si 3s- and 3p-derived features at higher binding energies. The V 3p, Mo 4p, Ta 5p, Ta 4f, and Si 2p coreemission features are also shown. Self-consistent band calculations for a series of cubic silicides MSi_3 , MSi_3 , and M_3Si_3 (*M* denotes V or Mo) predict dominant metal *d* character within 5 eV of E_F , Si s states centered at about -10 eV, Si p states centered near -5 eV, and substantial *M*-Si hybridization, in agreement with experiment.

INTRODUCTION

There is a great deal of interest in the interface between a transition-metal silicide and silicon.¹⁻⁸ Much of this interest is related to the technological importance of these Schottky barriers and their use in electronics devices. Within the last few years major progress has been made toward understanding the electronic structure of several silicide-Si interfaces. Recent attention has focused on the junction itself and the dynamics involved in forming a junction *in situ*, e.g., by metal deposition on Si followed by thermal treatments to form a thin silicide overlayer. Remarkably, there have been no studies until now of the electronic structure of bulk silicides; only the amorphous Pd-Si glasses⁹⁻¹¹ have been examined.

Experimental and theoretical studies of bulk silicides identify the roles of the metal and silicon in the band structure, reveal the metal-silicon mixing or hybridization, and contribute to the understanding of chemical bonding. Further, by identifying the electronic properties of the bulk silicide, it becomes possible to distinguish between bulk silicide properties and intrinsic interface properties and ultimately understand the interface evolution from silicon metal to silicon silicide metal.

In this paper, we present the results of a photoelectron spectroscopy study of three representative refractory metal disilicides, VSi_2 , $TaSi_2$, and $MoSi_2$. The photoemission measurements, conducted with synchrotron radiation, reveal trends in the three related body-centered-tetragonal disilicides. Total and *l*-decomposed densities of states were calculated for a series of V-Si and Mo-Si compounds in the Cu_2Au and CuAu structures in order to serve as a guide in the interpretation of observed features in the disilicide spectra. The calculations offer important insight into the band structure of silicides, including the dependence on the atomic ratio of M to Si. The combined experimental and theoretical studies allow us to identify the band-structure regions where the metal-derived states and the silicon-derived features are most important. These results help us understand the physics of silicides; it will remain for later calculations to examine the details of the specific silicide.

EXPERIMENTAL AND THEORETICAL TECHNIQUES

Samples of the bulk disilicides of V, Mo, and Ta were prepared by arc melting the high-purity constituents in a nonconsumable arc furnace on a water-cooled copper hearth.¹² The materials (~50 g) were melted under a purified Ar atmosphere using a water-cooled tungsten tip electrode (straight polarity, approximately 300 A). The resulting buttons were flipped and remelted at least five times to ensure homogeneity. Samples were cut for metallographic examination and for metal analysis. Optical metallographic examination showed grains up to $\sim 1 \times 4$ mm. VSi₂ and TaSi₂ samples, when polished and electropolished (12%) by volume sulfuric acid in methanol at 200 K) and viewed under 320 magnification, were essentially single phase. MoSi₂ had slight amounts of intragranular second phase that appeared bluish against the grey silicide matrix background. Such secondphase effects are insignificant as concluded, for

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FIG. 1. (a) Comparison of an experimental photoelectron energy distribution curve for VSi₂ with l-projected state densities for V₃Si (Cu₃Au structure), VSi (CuAu structure), and VSi₃ (Cu₃Au structure). The theoretical partial-state densities were calculated using the augmented-spherical-wave method developed by Williams, Kubler, and Gelatt. The calculations predict, and the experiment confirms, that the primary character of the states within ~5 eV of E_F are metal d derived. The deeper lying bands are primarily 3s-3p derived. (b) Results for Mo-Si analogous to those of VSi [see (a)].

example, by examining the Si 2p core emission (see Fig. 1 and discussion below).

The disilicides of V, Ta, and Mo are brittle and they fracture easily; they are also hard and are highly resistant to chemical attack even at elevated temperatures. This last property has made several of the refractory silicides attractive in technological applications. These disilicides have high melting points, low vapor pressures, and are relatively easy to prepare in bulk form. The silicides of V and Ta crystallize in the $CrSi_2 C40$ structure. The $MoSi_2$ crystal structure is bodycentered-tetragonal (C1 1b structure type, $MoSi_2$ structure).¹³

All measurements were performed in a bakeable, ultrahigh-vacuum photoelectron spectroscopy system (base pressure 3×10^{-11} Torr, operating pressures for these runs was $4-5 \times 10^{-11}$ Torr). The arc-melted buttons were cut to give posts $\sim 2 \times 3 \times 10$ mm³ which were mounted onto copper sample holders.¹⁴ These were loaded onto a bank having a capacity of ~ 20 for extended runs. Before the measurements, samples were removed from

the bank with an $x-y-z-\phi$ -flip-tilt manipulator. fractured in situ with a sharpened tungsten cleaving tool, and positioned at the common focus of the monochromatic radiation beam and the electron energy analyzer. Several cleaves could usually be made with each post. A detailed discussion of the geometry of the systems can be found in Ref. 15. The radiation was monochromatized with a 3 m toroidal grating monochromator after being emitted by orbiting electrons in the 240-MeV electron storage ring Tantalus at the University of Wisconsin-Madison. Photoelectron energy distribution curves were measured in photon energy increments of 1-2 eV for $9 \le h\nu \le 90$ eV with overall resolution (electrons plus photons) of about 0.4 eV. The Si 2*p* core levels were studied at $h\nu = 140$ eV.

The energy-band calculations are based on the local-density approximation to electronic exchange and correlation effects and on the augmentedspherical-wave (ASW) procedure for the solution of the effective one-electron equations. The ASW method developed by Williams, Kubler, and Gelatt is the spherical-wave analog of Slater's aug-



(a)

mented-plane-wave (APW) method and is closely related to Andersen's linear combination of muffin-tin orbitals (LMTO) method.¹⁶ The calculations are self-consistent (calculated electronic charges for successive iterations agree to within 0.001 electrons within the Wigner-Seitz sphere), parameter free (the only inputs were the atomic numbers and the structure type), and correspond to theoretical equilibrium (the atomic spacing was systematically varied until the total energy was minimized).

RESULTS AND DISCUSSION

The calculated l-decomposed density of states for VSi₃ (Cu₃Au crystal structure), VSi (CuAu), and V_3 Si (Cu₃Au) are shown in Fig. 1(a). The analogous results for the Mo-Si compounds are shown in Fig. 1(b). The different scales for the theoretical results reflect the different numbers of atoms (and electrons) per unit cell. For each series of calculations, we find the silicon s states centered at approximately -10 eV, the silicon p states centered at approximately 4-5 eV below E_F , and the metal d states near E_F and extending down to -5 eV. Calculations for VSi and MoSi with the CsCl crystal structure show the d character more strongly peaked near E_F (~2 eV of E_F) but with approximately the same overall width (~5 eV). As shown in Fig. 1, the widths of the Si 3s and Si 3p derived bands increase with increasing Si content and they shift to somewhat higher binding energy. Although calculations of the disilicide (CaF_2) were beyond the present scope of our computer codes, we expect the density-of-states features to be gualitatively similar to those shown. Also shown in Figs. 1(a) and 1(b) are photoelectron energy distribution curves for VSi_2 and $MoSi_2$, respectively, measured with photon energies of 78 eV, i.e., sufficiently high that density-of-states features are emphasized.

Photoelectron energy distribution curves measured for VSi₂ are shown in Fig. 2(a) for $9 \le h\nu$ ≤ 140 eV. The dominant feature within ~3 eV of E_F reflects the V-derived *d* character and the Fermi level falls in a region of high, but diminishing, state density. The *d*-band peak at -1.6 eV is seen for all photon energies and a relatively weak feature is visible at about -0.8 eV [better seen in Fig. 2(b)]. The calculated density of states supports the association of the dominant feature with the V-derived *d* bands even though the experimental details are not reproduced in detail.

Structure below the *d* bands can be associated with the Si-derived *s* and *p* bands. Features in those bands are better seen at some photon energies than at others. For $h\nu = 37$ eV, the minimum between the *d* bands and the Si-derived bands falls ~4 eV below E_F , and there are maxima at -5.5, -7.2, and -10.4 eV. For lower photon energies the background from inelastically scattered secondaries obscures the Si-derived features; e.g., only the features at -5.5 and -7.1 eV can be identified with complete confidence for $h\nu$ =20 eV. The total width of the Si-V valenceband emission is ~12 eV as predicted by the VSi or VSi₃ calculations.

In Fig. 2(a) for $h\nu = 50$ eV, we show Auger emission (MVV) arising from the V 3*p* cores (binding energy 37.4 eV). For lower photon energies $(37 \le h\nu \le 50$ eV including the He resonance line at 40.8 eV), the Auger feature overlaps the valence-band direct emission.

In Fig. 2(a), we show the Si 2p doublet, the line shape of which is consistent with a spin-orbit splitting of 0.6 eV.¹⁷ From a deconvolution of the 2p structure, we identify the binding energies to be 99.3 and 99.9 eV for the $2p_{1/2}$ and $2p_{3/2}$ levels, respectively, referenced to the Fermi level.

Examination of the Si2p feature shown in Fig.



FIG. 3. A collection of energy distribution curves for TaSi₂ showing spectra very similar to those for VSi₂. The *d* bands are wider, but the overall character remains the same. The core-level emission from the Ta 4*f* doublet and 5*p* doublet is shown in the top of the figure together with the Si 2*p* portion of the spectrum taken at $h \nu = 140 \text{ eV}$.



FIG. 4. A collection of energy distribution curves for MoSi₂. The prominent features near E_F are interpreted as *d* derived while the deeper features reflect Si-derived bands. Core-level features from Mo and Si are shown at the top of the figure.

2(a) indicates that Si is present only in a single charge state. Oxide contamination would introduce a second feature shifted toward higher binding energy. The presence of a second phase or of elemental Si at the surface would tend to broaden the Si2p feature (at $h\nu = 140$ eV the kinetic energy of the exc⁻ ed electron is ~40 eV, the escape depth of the electron is only ~5 Å). The full width at half maximum (~1.1 eV) is consistent with what has been observed for Si in angle-resolved photoemission studies of V₃Si (Ref. 18), also using a 3 m toroidal grating monochromator (the resolution of our measurements is limited primarily by the resolution of the monochromator, ~0.6 at $h\nu = 140$ eV).

In the overview figure for VSi₂ [Fig. 2(a)], we also show the V 3*p* core emission structure as measured with $h\nu = 90$ eV. The binding energy shown is 37.4 ± 0.2 eV, compared to 37.2 ± 0.2 eV for elemental V (Ref. 19) or 37.1 eV for vanadium in V₃Si.¹⁸

An expanded energy view of the initial states of VSi_2 within ~5 eV of E_F is shown in Fig. 2(b). Two well-defined structures can be identified in the VSi_2d bands at 1.5–1.6 eV and ~0.8 eV below E_F . These features do not disperse with photon energy, although they do vary in relative strength.

As shown in Fig. 2(a), emission from the Si-

PHOTOELECTRON EMISSION INTENSITY (Arb. units) Mo Si₂ $h\nu = 78 \text{ eV}$ Ta Si, VSi2 76 METAL d BANDS Si - 3: Si ρ 20 18 16 14 12 10 8 4 2 0 6 ENERGY BELOW EF (eV)

FIG. 5. A comparison of energy distribution curves for VSi₂, TaSi₂, and MoSi₂. The *d* bands of VSi₂ are narrower than those of either MoSi₂ or TaSi₂ and the density of states at E_F is higher, as judged by the strength of the emission at the trailing edge of the Fermi cutoff. Features within the Si *p*-derived bands are relatively independent of the metal contribution in these disilicides. The 4s band at approximately -11 eV is also unchanged in general appearance.

derived s - and p-states is low at energies of 50-60 eV but is greater at higher photon energies and the d bands remain prominent for all photon energies. In part this is an artifact of the normalization of the spectra since the spectra have been normalized to keep the d-band intensity approximately constant.

In order to identify trends and to support our interpretation of the spectra for VSi_2 , we have extended the measurements to include bulk samples of $TaSi_2$ and $MoSi_2$ as shown in Figs. 3 and 4, respectively. In Fig. 5 we compare the three metal disilicides. For VSi_2 , the width of the *d*-derived band is considerably narrower than in isoelectronic $TaSi_2$ or in $MoSi_2$. The peak in the *d* bands shifts from about -1.6 eV in VSi₂ to about -2.4 eV in $TaSi_2$ and about -2.2 eV in $MoSi_2$. At the same time, the Si-derived features have shifted very little, a trend supported by the MoSi calculations of Fig. 1(b). The Si 3s states fall at approximately -11 eV for all three silicides and the two features in the Sip bands occur at roughly 5.8 and 7.5-8 eV below E_F . Comparison of the three spectra of Fig. 5 suggests that the density of states at E_F is higher in VSi₂ than in either TaSi₂ or MoSi₂ as indicated by the relative heights of the dominant peak and the trailing edge of the Fermi-level cutoff. To our knowledge, however, there have been no heat capacity measurements which could support this preliminary observation.

Core-level spectra for $TaSi_2$ and $MoSi_2$ are also shown in Figs. 3 and 4. From Fig. 3 it can be seen that the Ta 4f levels have binding energies of 22.5 and 24.4 eV (spin-orbit splitting of 1.9 eV), compared to 21.57 and 23.48 \pm 0.05 eV for bulk 4f level in single crystal Ta.²⁰ The Ta 5p_{1/2} binding energy is 33.5 eV and that of the 5p_{3/2} is 42.4 eV (splitting 8.9 eV). For MoSi₂, the 4p_{3/2} core has a binding energy of 35.2 eV and the spin-orbit splitting is approximately 2.1 eV.

CONCLUSIONS

We have found that the electronic structure of the refractory metal silicides VSi₂, MoSi₂, and TaSi₂ is dominated by metal *d*-derived character within ~5 eV of the Fermi level and that the Si *s* and *p*-derived bands extend to ~12 eV below E_F . We have observed that the *d* bands are wider for TaSi₂ than VSi₂, as was expected. Our interpretation of the observed features according to Si-*sp* or metal-*d* character is supported by self-consis-

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tent calculations of the total and l-projected density of states.

The *l*-decomposed state densities provide a clue to understanding the chemical bonding in these compounds. As in the case of Pd silicides,²¹ strong interactions between metal-*d* and silicon-*p* states lead to the formation of hybridized bonding and anti-bonding complexes. The bonding complex, pinned at the lower edge of the metal-*d* band, is completely occupied. The antibonding complex is usually diffused (except for the case of the metalrich compounds) and well above E_F .

ACKNOWLEDGMENTS

The authors are grateful for the able assistance of many colleagues and for helpful discussions with D. T. Peterson, G. W. Rubloff, G. Margaritondo, D. E. Aspnes, and J. E. Rowe. This work has been supported in part by the United States Department of Energy, Division of Materials Research, Office of Basic Energy Sciences (Contract No. DE-AC-02-80ER10584 to Weaver, W-7405-eng-82 to Ames Laboratory); the Synchrotron Radiation Center is supported by the NSF (Grant No. DMR78-21888).

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